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9R. 1104 #4/D
6-8-93
D. Brooks

Docket: 0756-775

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re PATENT application of)
Takashi INUSHIMA et al.)
Serial No. 07/971,242,) Art Unit: 1104
Filed: September 8, 1992) Examiner: G. Goudreau
For: CVD APPARATUS) Date: May 21, 1993

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AMENDMENT AND INFORMATION DISCLOSURE STATEMENT

Honorable Commissioner of Patents and Trademarks
Washington, D.C. 20231

Sir:

In response to the Office Action of April 22, 1993, please amend the subject application as follows.

IN THE CLAIMS:

Cancel claims 7-15 and add new claims 16-30.

-16. A method of forming a film on a substrate comprising the steps of:

placing a substrate in a reaction chamber;

introducing a reactive gas comprising at least TEOS;

exciting said reactive gas by supplying photo and electrical energies into said reaction chamber; and

depositing a film on said substrate by CVD.

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